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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kiyoshi IRINO

Serial No.: Divisional of SN 08/917,936

Prior Art Unit: 2811

Filed: Herewith

Examiner: Not Yet Assigned

For: METHOD OF FABRICATING A SEMICONDUCTOR
DEVICE CONTAINING NITROGEN IN A GATE OXIDE
FILM (As Amended)

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 CFR 1.97(b)

Assistant Commissioner for Patents

Washington, D.C. 20231

October 27, 1999

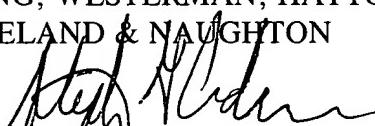
Sir:

This Information Disclosure Statement is being filed in order to comply with Applicant's duty of disclosure under 37 CFR 1.56. The documents listed on the Form PTO-1449 were made of record in parent application Serial No. 08/917,936 filed August 27, 1997. Accordingly, copies of the references are not attached.

The Commissioner is authorized to charge our Deposit Account No. 01-2340 for any fee which is deemed by the Patent and Trademark Office to be required to effect consideration of this statement.

Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI,
McLELAND & NAUGHTON


Stephen G. Adrian
Attorney for Applicants
Reg. No. 32,878

Atty. Docket No. 970901A
1725 K Street, N.W., Suite 1000
Washington, DC 20006
Tel: (202) 659-2930
Fax: (202) 887-0357
SGA/kk